Title: "Process Condition Sensing Wafer and Data Analysis

System"

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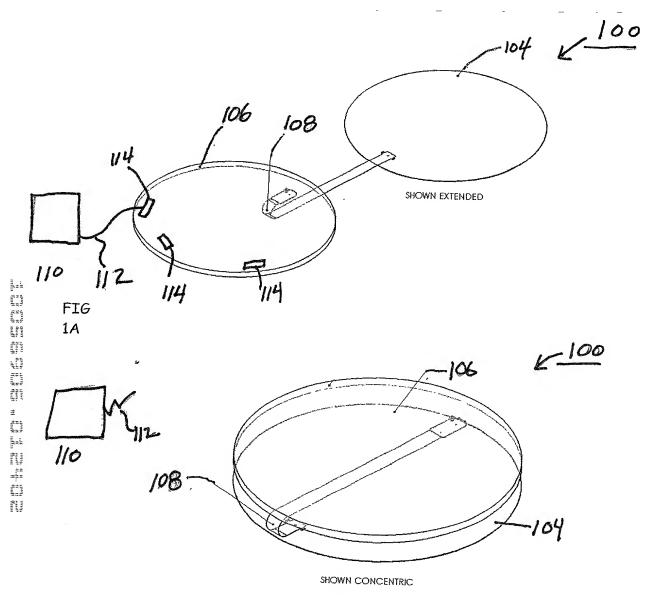
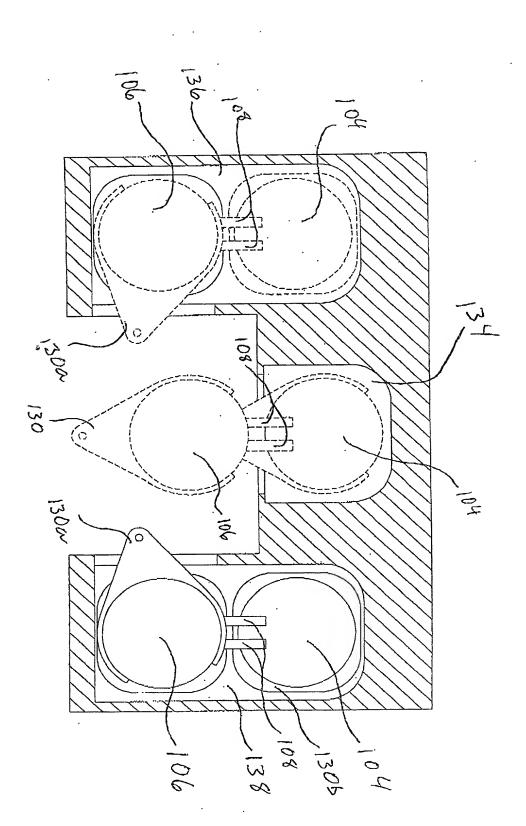


FIG 1B

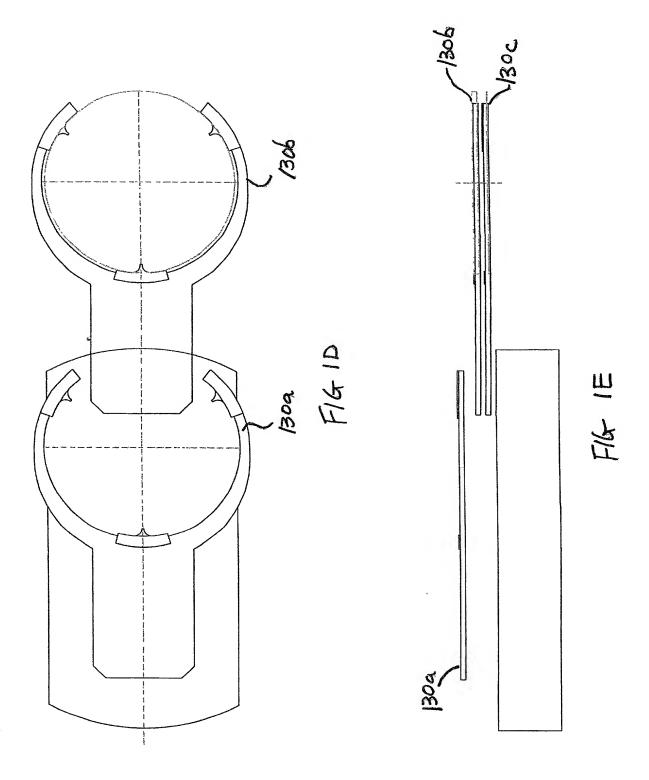
Title: "Process Condition Sensing Wafer and Data Analysis

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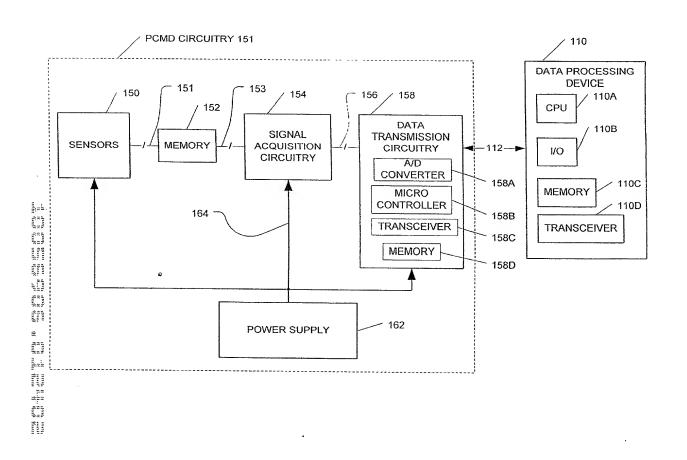
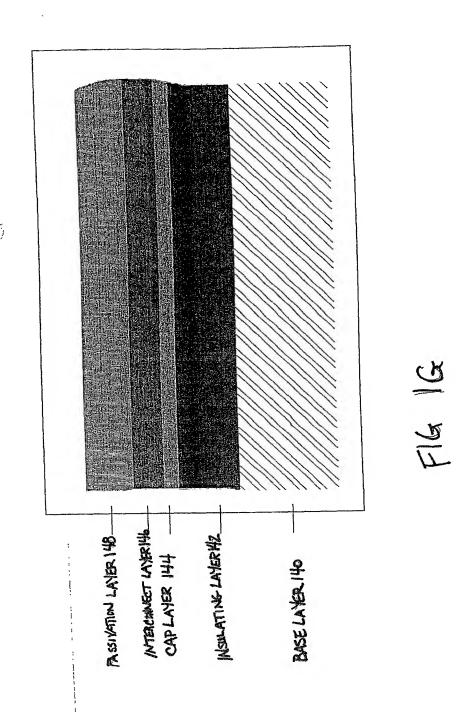


FIG 1F

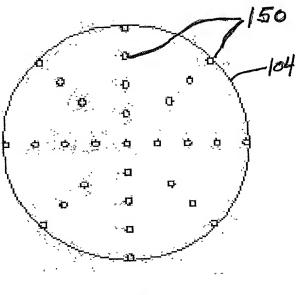
Inventor: Wayne Renken Title: "Process Condition Sensing Wafer and Data Analysis System"

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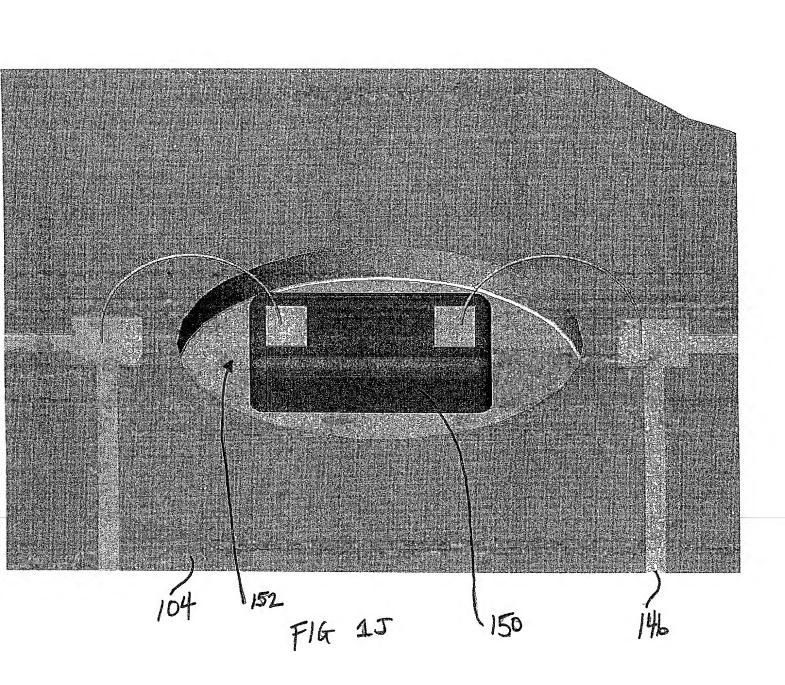
Inventor: Wayne Renken Title: "Process Condition Sensing Wafer and Data Analysis

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Inventor: Wayne Renken Title: "Process Condition Sensing Wafer and Data Analysis System"

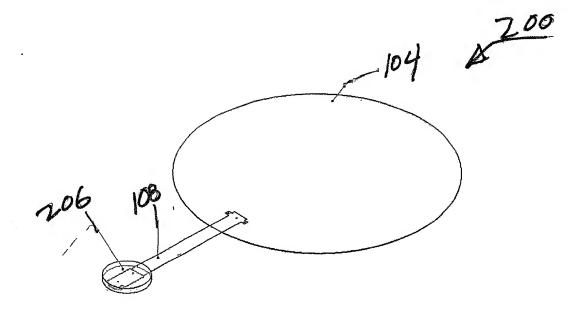
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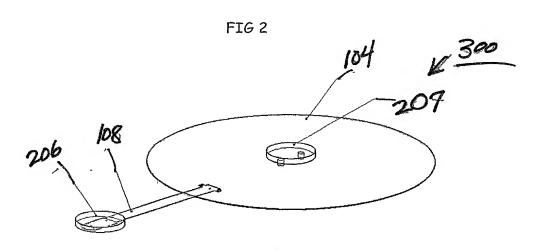
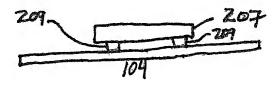


FIG 3A



F16: 3B

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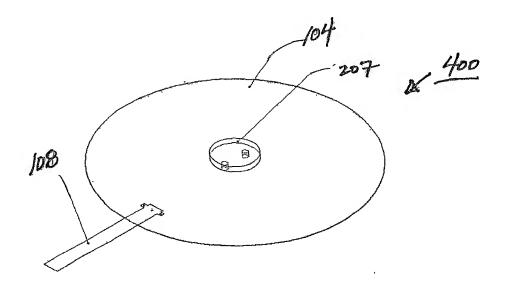


FIG 4

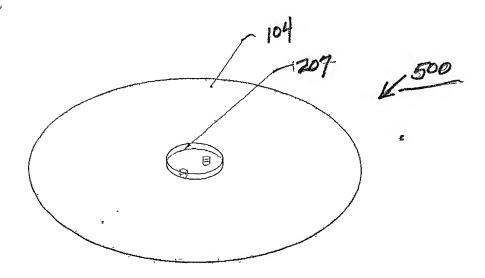


FIG 5

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Atty. Dkt. No.: M-12467 U

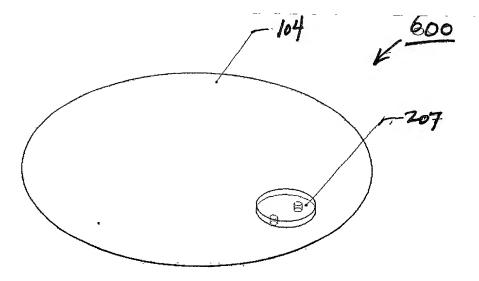


FIG6

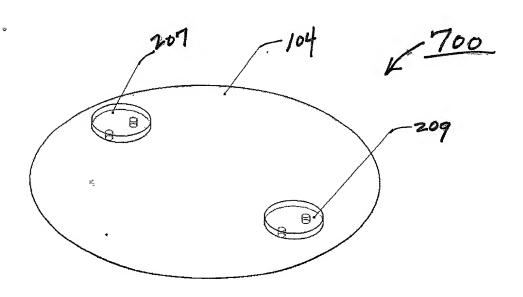


FIG 7